



Study of plasma meniscus including the surface produced negative ions by using PIC-MCC simulation

K. Miyamoto^{a)}, K. Hayashi^{b)}, K. Hoshino^{b)}, and A. Hatayama^{b)}

a) Naruto University of Educationb) Faculty of Science and Technology, Keio University

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Introduction

It is essential for a hydrogen negative ion source to generate the negative ion beams with good beam optics as well as with the high current density. For example, a negative ion beamlet with a divergence angle of $3 \sim 7$ mrad is required for the negative ion source in the negative ion based NBI for ITER [1, 2].

If the negative ion **beam divergence angle is large**, the negative ion beam will impinge on the acceleration grid and other components during beam acceleration and transport, and then causes **the heat loads**, **loss of the negative ion beam current**, **and break down of voltage holding** due to the resultant secondary electrons.

Therefore, the negative ion beam optics has been studied intensively in development of the hydrogen negative ion sources. In general, an **ion beam optics depends on the shape of plasma meniscus**, which is **an ion emitting surface**.

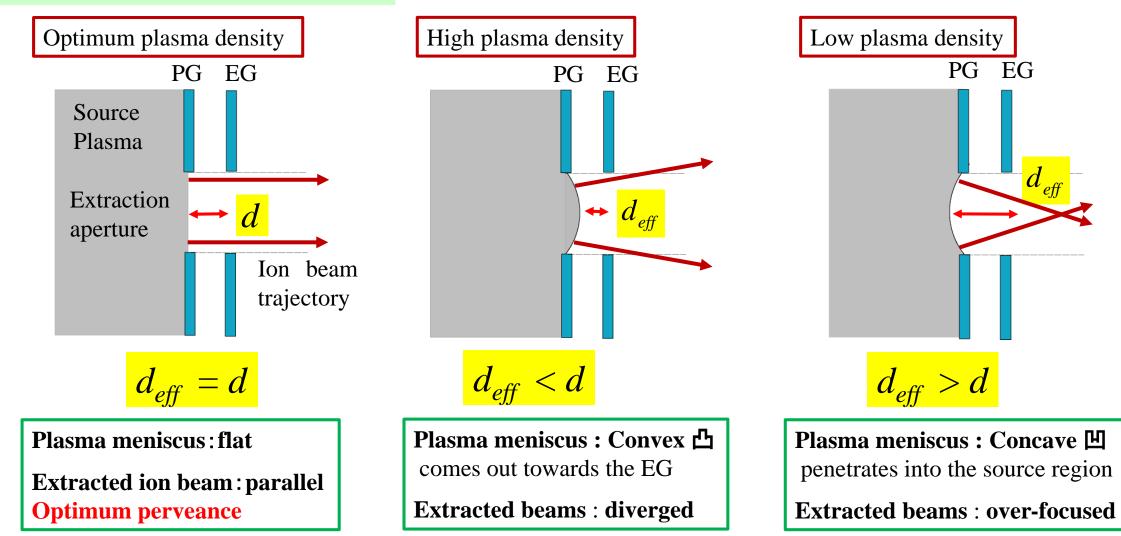
[1] Hemsworth S R, Boilson D, Blatchford P, Palma D M, Chitarin G, Esch de L P H, Geli F, Dremel M, Graceffa J, Marcuzzi D 2017 New J. Phys. 19 025005.

[2] M. J. Singh, D. Boilson, A. R. Polevoi, T. Oikawa, and R. Mitteau 2017 New J. Phys. 19 055004.

Relation between shape of plasma meniscus and ion beam optics

Control of **effective distance** d_{eff} **between** the Plasma Grid (**PG**) and the Extraction Grid (**EG**) (or equivalently **the position of the plasma meniscus**) is very **important** to obtain **good beam quality.**

d: geometrical distance between PG and EG



What are the key parameters to determine/control d_{eff}?
How d_{eff} depends on these key parameters ?
How to control the plasma meniscus ?

For ordinary plasmas with single positive ions and electrons: well-known simple theory tells us:

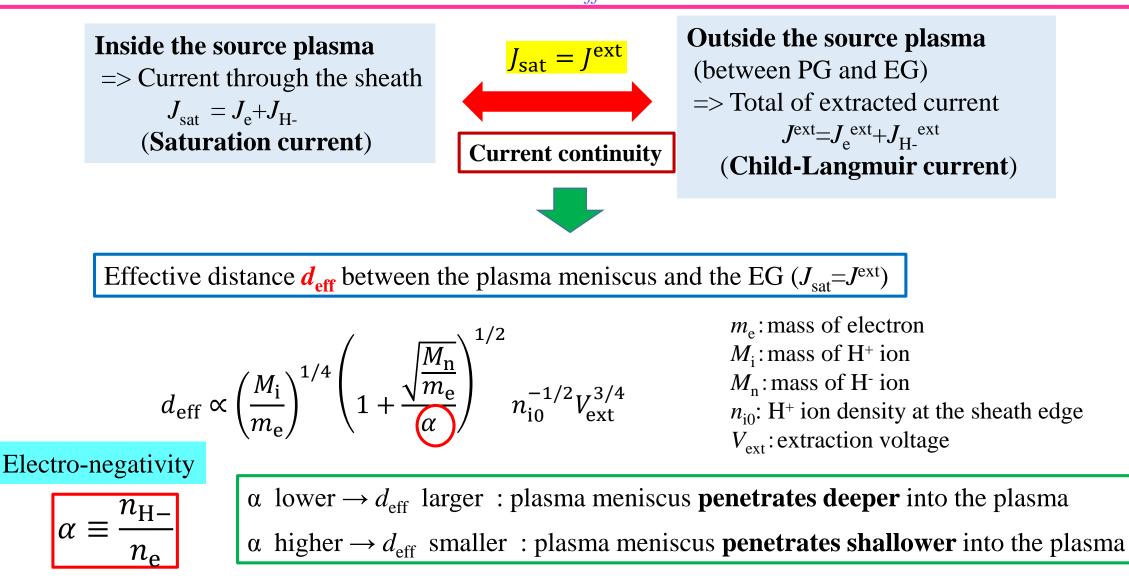
$$d_{\rm eff} = \frac{2^{5/4}}{3} \exp\left(\frac{1}{4}\right) \left(\frac{\varepsilon_0}{e}\right)^{1/2} n_{\rm p}^{-1/2} \left(\frac{kT_{\rm e}}{e}\right)^{-1/4} V_{\rm ext}^{3/4}$$

M: mass of a positive ion n_p : plasma density T_e : electron temperature V_{ext} : extraction voltage

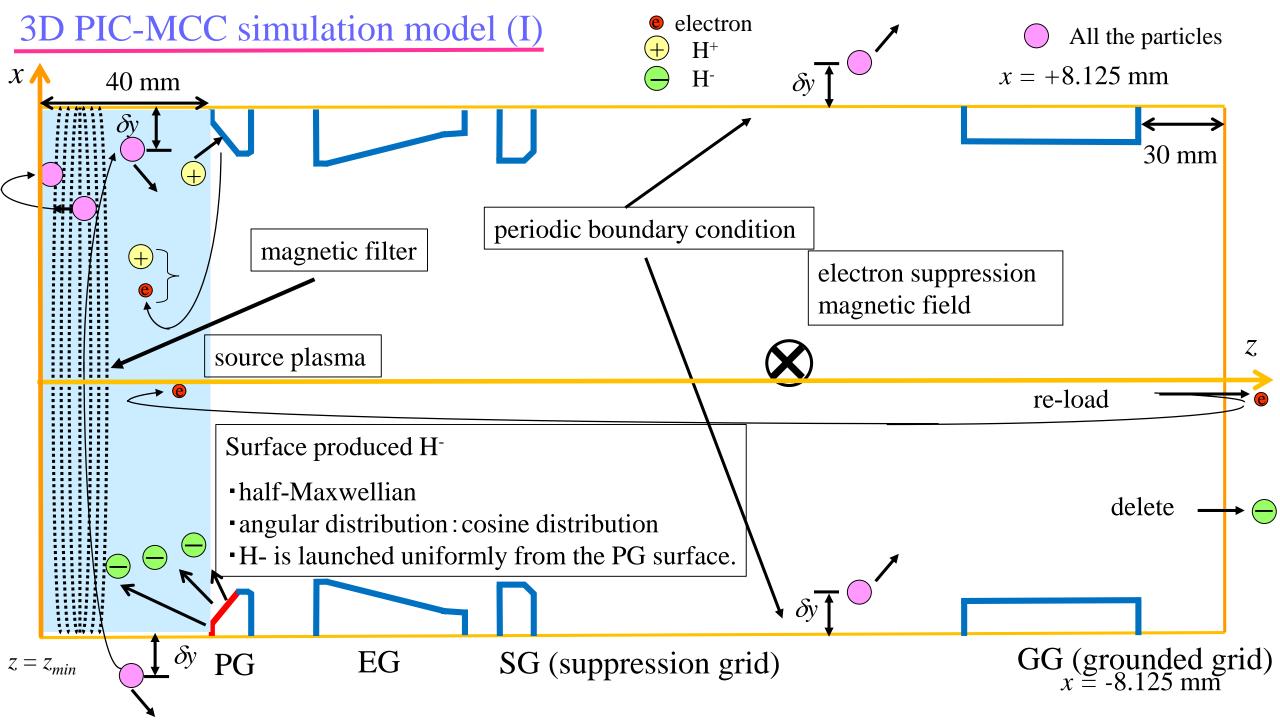
However, for the electronegative plasma including the surface produced H⁻ ions in the negative ion sources, the key parameters to control the plasma meniscus and the dependence on these parameters are still unclear.

In this study, the plasma meniscus and relevant physical structure such as the sheath in the electronegative plasma including the surface produced H⁻ ions was investigated by using both analytical theory and 3D PIC-MCC simulation.

Analytic theory of the effective distance d_{eff} including surface produced H⁻ ions



Electro-negativity α near the PG is a very important parameter to control d_{eff} (the plasma meniscus).



3D PIC-MCC simulation model (II)

Physical parameter	Value
Electron temperature	1 eV
Hydrogen ion temperature	0.3 eV (H ⁺) 0.1 eV(volume produced H ⁻) 1 eV(surface produced H ⁻)
Electron density	$1.8 \times 10^{17} \text{ m}^{-3}$
Hydrogen atom temperature	0.3 eV
Hydrogen molecule temperature	0.1 eV
Hydrogen molecular density	$1.88 \times 10^{19} \text{ m}^{-3} \text{ (at 0.3 Pa)}$
Density ratio n _H /n _{H2}	0.5

In order to investigate the effect of electro-negativity ($\alpha \equiv n_{\rm H}/n_{\rm e}$) on the effective distance $d_{\rm eff}$, the following numbers of the surface produced H⁻ ion super-particles per timestep were surveyed:

Number of H- particles / time step / process	Surface produced H ⁻ ion flux from PG (A/m ²)
20	39
60	146
100	255

3D PIC-MCC simulation model (III)

•The following collisions related to the H⁻ ions are taken into account: Coulomb collision : H⁻ – H⁺, H⁻ – H⁻ Charge exchange collision : H⁻ (fast)+ H(slow) \rightarrow H⁻ (slow)+ H(fast) Elastic collision : H⁻ – H, H⁻ – H₂ Mutual neutralization : H⁺ + H⁻ \rightarrow H + H

Other simulation conditions

•Initial super-particle numbers : Electron (8.715 × 10⁷), H⁺ ion (1.245 × 10⁸), H⁻ ion (3.735 × 10⁷)

10 particles per mesh in average

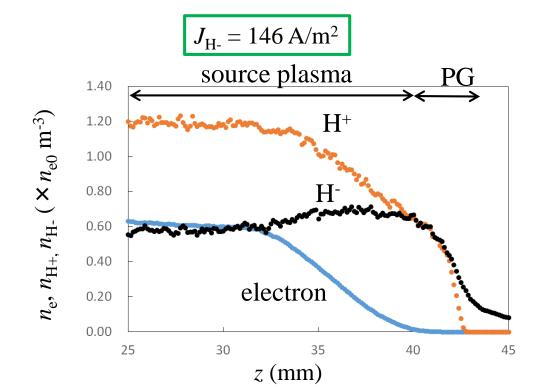
•Neutral particles (H, H_2) are assumed to be the background particles.

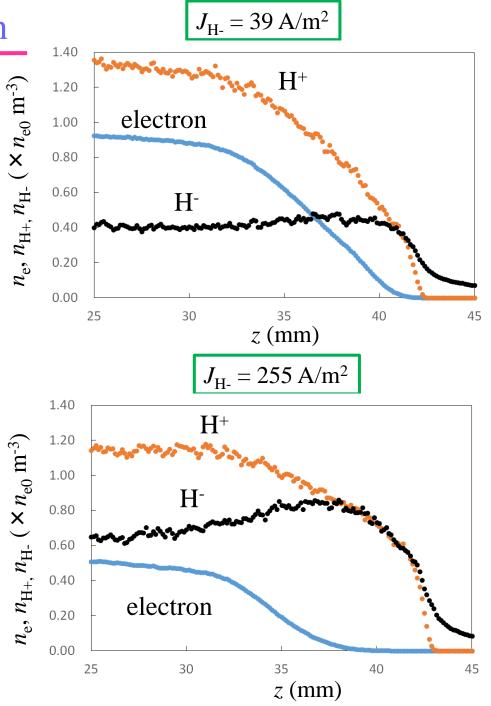
• Extraction and acceleration voltage:
$$V_{PG} = 0$$
 V, $V_{ext} = V_{SG} = 2.7$, $V_{acc} / V_{ext} = 22$

Spatial distribution of electron, H⁺ on, and H⁻ ion

• Spatial distributions of electron H^+ ion, and H^- ion densities along the *z*-axis are compared.

•The ratio $n_{\rm H}/n_{\rm e}$ increases as the flux of surface produced H⁻ particles per time increases.

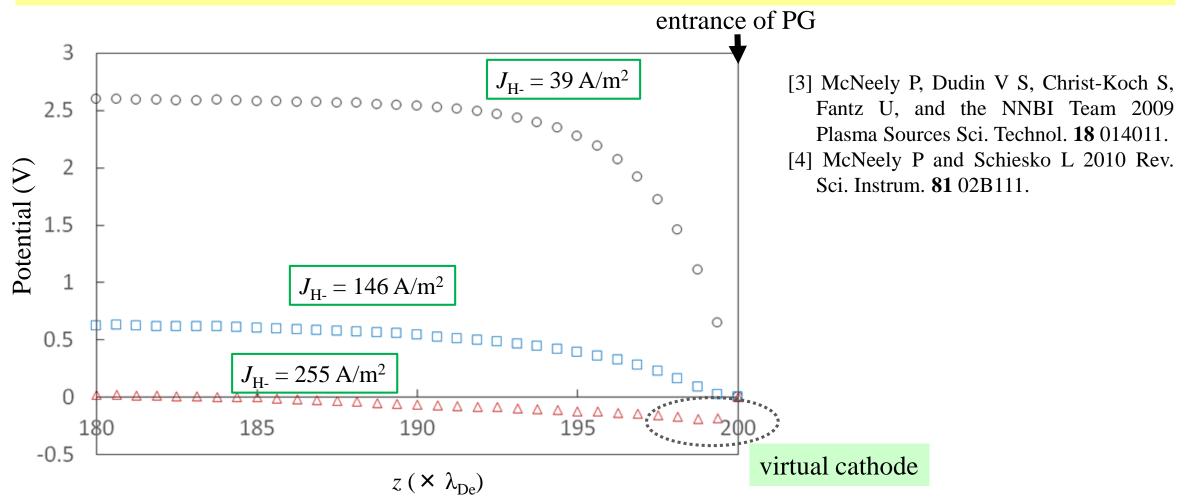




Potential profile in the sheath

•Sheath potential becomes lower compared with that without the surfaced produced H⁻ ions, which agrees with the experimental results [3, 4].

- •Sheath potential decreases with the increase in the surface produced H⁻ ion flux.
- The onset of virtual cathode appears with the increase in the surface produced H⁻ ion flux.

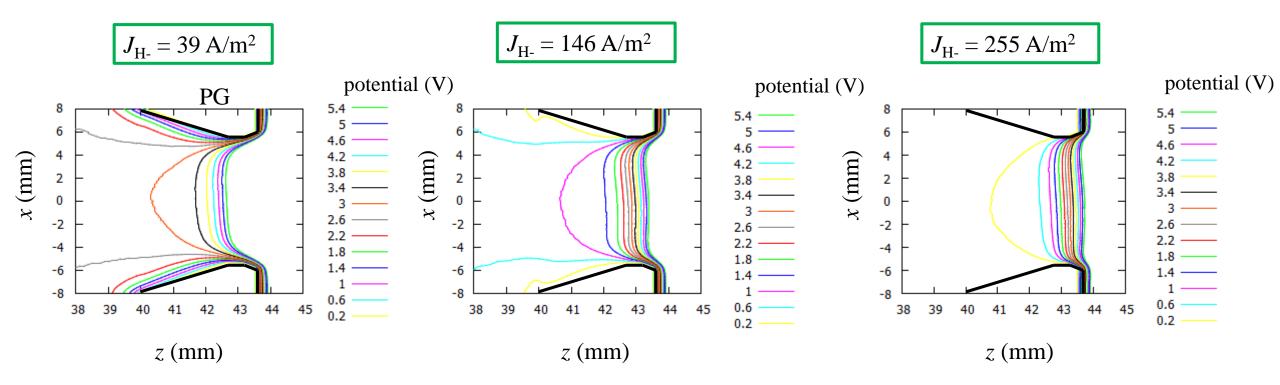


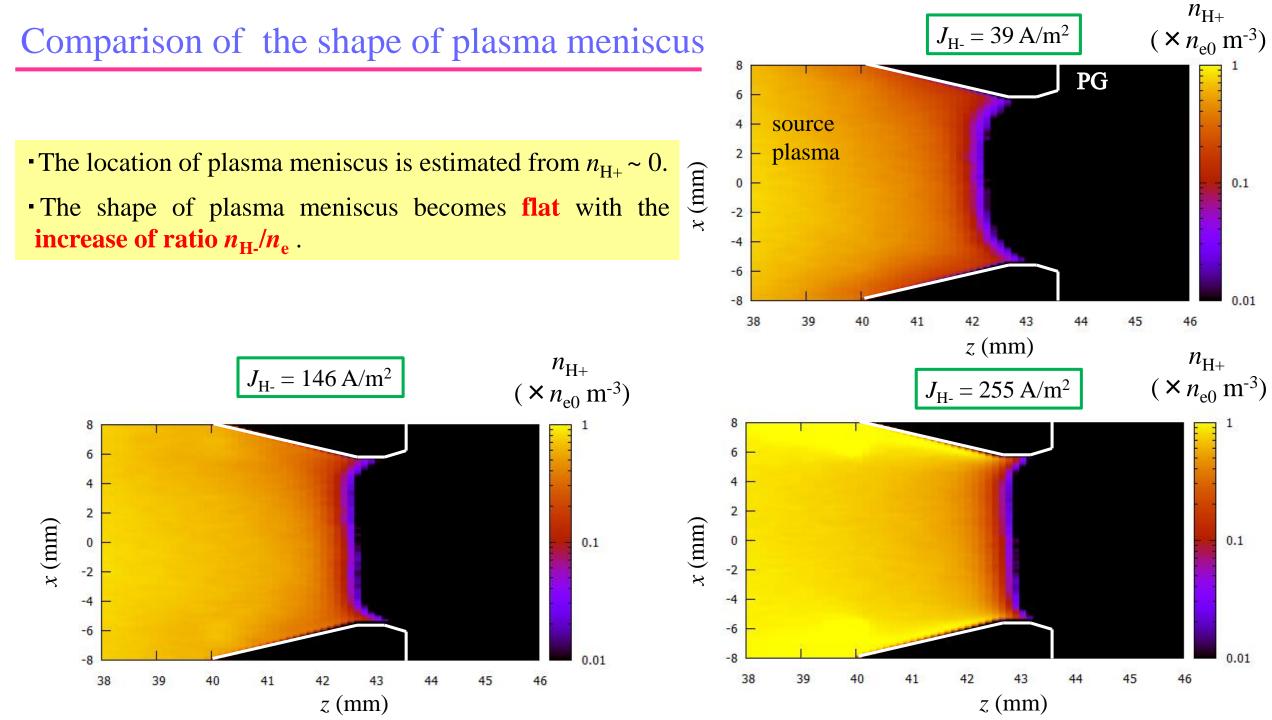
Effect of the ratio $n_{\rm H}/n_{\rm e}$ on the penetration of electric field

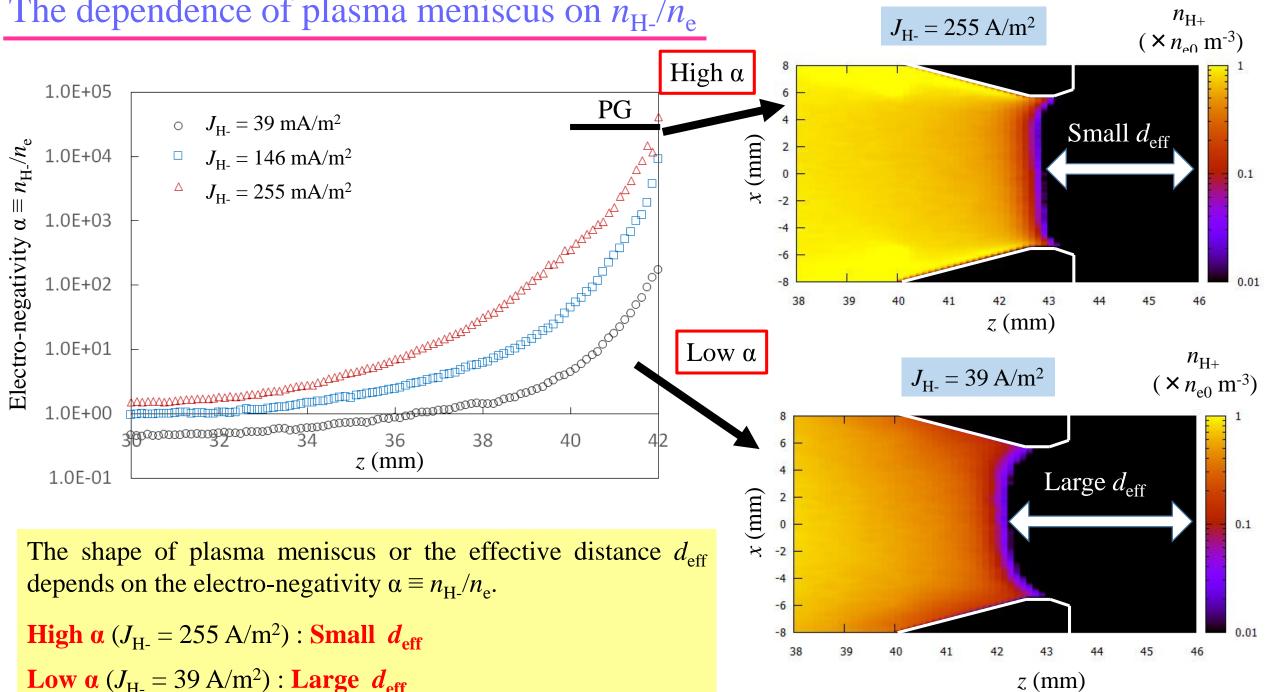
• Penetration of electric field for extraction becomes shallower with the increase of ratio $n_{\rm H}/n_{\rm e}$.

•For the small ratio $n_{\rm H}/n_{\rm e}$, the surfaced H⁻ ions are extracted directly from the PG surface rather than enter into the bulk plasma.

Contour map of the electrostatic potential near the PG

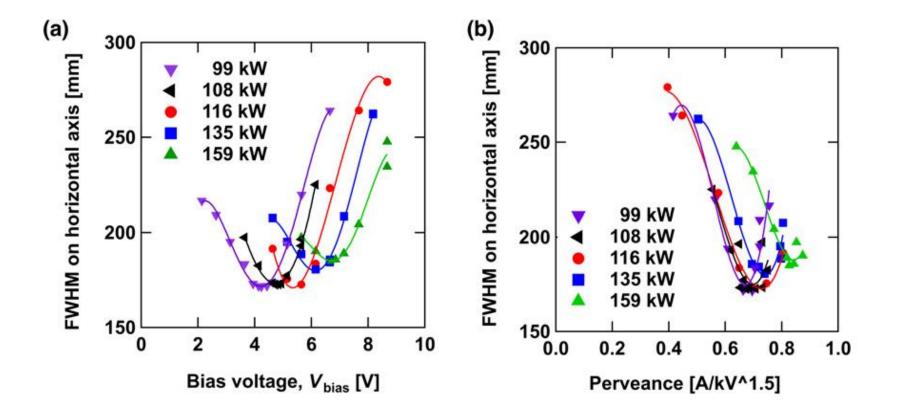






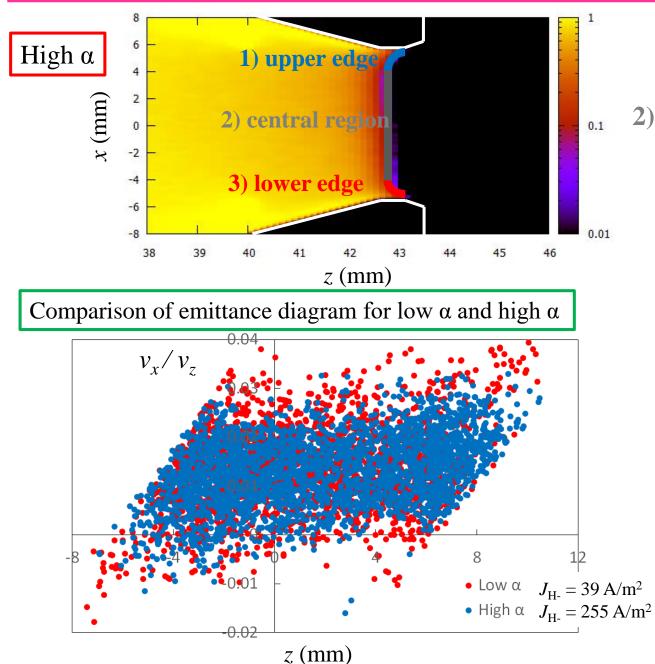
The dependence of plasma meniscus on $n_{\rm H}/n_{\rm e}$

The experimental result in ref. [5] may support the present simulation result that the shape of the plasma meniscus depends on electro-negativity α .

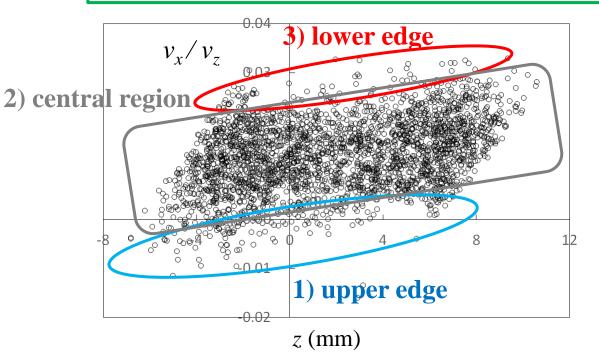


[5] Kisaki M, Ikeda K, Nakano H, Tsumori K, Fujiwara Y, Haba Y, Kamio S, Nagoka K, Osakabe M 2018 Plasma Fusion Res. 13 1205110.





Emittance diagram at the location of 30 mm from the exit of GG



 The H⁻ ions extracted from the edge of plasma meniscus become more pronounced for the low electro-negativity α in the emittance diagram.

• It is verified that the ratio of $n_{\text{H-}}/n_{\text{e}}$ affects the H⁻ ion beam optics.

Summary and future plan

The plasma meniscus and relevant physical structure in the electronegative plasma with the surface produced H⁻ ions was investigated from analytical theory and 3D PIC-MCC simulation.

• It is shown that the distance d_{eff} , between the plasma meniscus and the extraction grid depends on the electro-negativity $\alpha = n_{\text{H}-}/n_{\text{e}}$ as well as the plasma density.

•Especially under the constant plasma density, Higher $\alpha \rightarrow$ **Smaller** d_{eff} , while Lower $\alpha \rightarrow$ **Larger** d_{eff}

 This dependence of the distance d_{eff} on the electro-negativity α is considered to be caused by the larger space charge effect of the H⁻ ions, preventing penetration of the electric field for H⁻ extraction into the source plasma.

The future plans for the study of the plasma meniscus and H⁻ ion beam optics are as follows: 1) A systematic comparison with the experimental result

2) Further investigation of the relevant physics of the plasma meniscus, for exampleasymmetry structure of the plasma meniscus

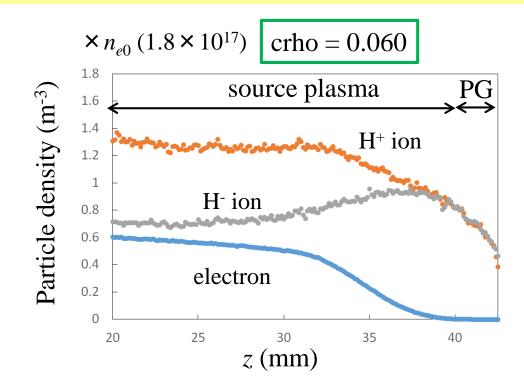
•relationship between extraction mechanism of surface produced H⁻ ions and beam optics

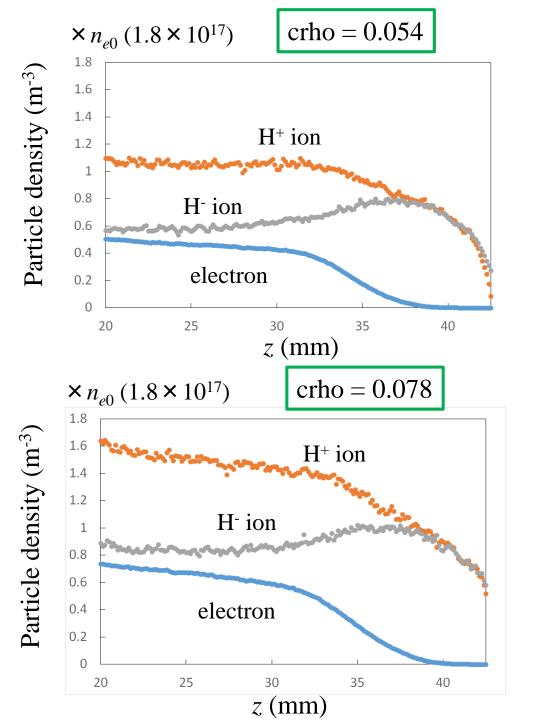
Dependence of shape of plasma meniscus on plasma density(I)

• The charged particle densities $n_{\rm e}$, $n_{\rm H+}$, and $n_{\rm H-}$ along the *z*-axis.

•In the simulation, the plasma density was varied by changing the weighting parameter "crho", which correspond to the number of real particles per super-particle of the simulation.

•The plasma density increases with increase in the value of crho.





Dependence of shape of plasma meniscus on plasma density (II)

- It is verified that he shape of plasma meniscus depends on the plasma density.
- •With the increase in the plasma density, the shape of plasma meniscus varies as follows:

